

Inventor: Garo J. Derderian et al.

Title: Atomic Layer Deposition Method of Forming an Oxide Comprising Layer on a Substrate

Assignee: Micron Technology, Inc.

INFORMATION DISCLOSURE STATEMENT

References -- See Attached Form PTO-1449

The attached form PTO-1449 is submitted in compliance with 37 CFR § 1.56. Pursuant to 1276 OG 55, August 5, 2003, no copies of cited U.S. patents or U.S. patent application publications are included, as the date of filing of this patent application occurs after June 30, 2003. No admission is made regarding whether all the submitted references are prior art.

Respectfully submitted,

Dated: 2-19-04

Attorney: 

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Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-2403		SERIAL NO. Unknown	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT: Garo J. Derderian et al.			
				FILING DATE February 19, 2004		GROUP Unknown	

U.S. PATENT DOCUMENTS							
*Examiner's Initials		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	6,403,414 B2	06/11/02	Marsh			
	AB	6,451,692B1	09/17/02	Derderian et al.			
	AC	6,454,912 B1	09/24/02	Ahn et al.			
	AD	6,495,458 B2	12/17/02	Marsh			
	AE	6,534,357 B1	03/18/03	Basceri et al.			
	AF	6,596,583 B2	07/22/03	Agarwal et al.			
	AG	6,613,656 B2	09/02/03	Li			
	AH	2003/0207540 A1	11/06/03	Ahn et al.			
	AI	2003/0207593 A1	11/06/03	Derderian et al.			
	AJ	2003/0227033 A1	12/11/03	Ahn et al.			

FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation
							Yes No
	AK						
	AL						

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)			
	AM		
	AN		
	AO		

EXAMINER	DATE CONSIDERED
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.